

PATENT AND LEGAL OPERATION  
1 RESEARCH CIRCLE, BLDG. K1-3A66  
SCHENECTADY, NY 12309  
TELEPHONE: (518) 387-7713, FAX: (518) 387-7751  
DIAL COMM: 8\*333-7713



GE CORPORATE  
RESEARCH AND  
DEVELOPMENT

# Fax

**CONFIDENTIALITY NOTE:**

This document is intended only for the use of the person to whom it is addressed; the document may contain information that is privileged, confidential, and exempt from disclosure under applicable law. If the reader of this message is not the intended recipient, or the employee or agent responsible for delivering it to the intended recipient, please immediately notify us by telephone, and return the original message to us at the above address without any dissemination, distribution or copying of this communication. Thank you.

---

**To:** Examiner Luk **From:** Ann Agosti *AM-A*

---

**Fax:** 703 872 9627 **Pages Including this sheet:** 5

---

**Phone:** 703 305 1558 **Date:** 12 November 2002

---

**Re:** IDS submitted with original application

---

**Comments:** I tried calling to discuss. Per your request, here is a copy of the IDS we submitted on 4 August 2000. We submitted it in a time period when this type of submission was acceptable and routine (under the impression it was proof that the items were actually cited previously). Subsequently, we have been informed that a new clean list is preferred. If you need a new clean list, please let me know. We will be happy to prepare one. Thank you, Ann

Serial No:

Docket N .: RD-25,905/USA

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: RENATO GUIDA, ET AL

Serial No.:

Filed:

Group Art Unit:

For: HIGH RESOLUTION ANTI-SCATTER X-RAY GRID AND LASER  
FABRICATION METHODINFORMATION DISCLOSURE STATEMENT CONTINUING APPLICATIONHonorable Assistant Commissioner of Patents  
Washington, DC 20231

SIR:

This Information Disclosure Statement is being filed under 37 C.F.R. §1.56 for a continuing application, which relies on the filing date of its parent application, such parent application being identified as:

U.S. Patent Application Serial No: 09/105,788

Examiner: K. Duda

Filed: 6/26/98

Group Art Unit: 1756

Inventor(s): Renato Guida, et al

Title: HIGH RESOLUTION ANTI-SCATTER X-RAY GRID AND LASER  
FABRICATION METHOD

Enclosed are copies of Forms PTO-1449 listing all "prior art" cited and submitted in the parent application and Form PTO-892 listing "prior art" cited by the Examiner in the parent application. Pursuant to 37 C.F.R. §1.98(d), no actual copies of the documents listed are being furnished to the PTO with this Information Disclosure Statement.

Respectfully submitted,



ANN M. AGOSTI  
PATENT COUNSEL  
REGISTRATION NO: 37,372  
TELEPHONE: (518) 387-7713

DATE: 4 August 2002

General Electric Company  
CRD Patent Docket Room 4A59  
PO Box 8, Bldg. K-1 Salamone  
Schenectady, New York 12301  
CUSTOMER NO: 006147